

03500.015382.



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

TAKAHARU KONDO, ET AL.

Application No.: 09/866,665

Filed: May 30, 2001

For: SILICON-TYPE THIN FILM  
FORMATION PROCESS, SILICON  
TYPE THIN FILM, AND  
PHOTOVOLTAIC DEVICE

Examiner: Alan D. Diamond

Group Art Unit: 1753

April 6, 2005

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action dated January 6, 2005, please amend the  
above-identified application as follows.

I hereby certify that this correspondence is being deposited with the  
United States Postal Service as first-class mail in an envelope addressed  
to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-  
1450 on April 6, 2005  
(Date of Deposit)

John A. Krause (Reg. No. 24,613)  
(Name of Attorney for Applicants)

Signature

April 6, 2005

Date of Signature